



PATENT  
Atty. Dkt. AMAT/6303.02/CPICOPPER/PJS

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Chung, et al.

Serial No.: 09/963,373

Confirmation No.: 6509

Filed: September 26, 2001

For: **INTEGRATION OF  
BARRIER LAYER AND  
SEED LAYER**

MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Group Art Unit: 2814

Examiner: Wai Sing Louie

**CERTIFICATE OF MAILING**  
**37 CFR 1.8**

## **SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

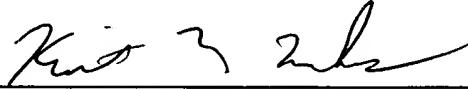
While the information submitted in this Supplemental Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Supplemental Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/6303.02/KMT.

Respectfully submitted,



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Attorney for Applicant(s)

Substitute for form 1449A/PTO

Application Number 09/963,373

**SUPPLEMENTAL INFORMATION  
DISCLOSURE STATEMENT BY  
APPLICANT**

(Use as many sheets as necessary)

Filing Date September 26, 2001

First Named Inventor Chung, et al.

Group Art Unit 2814

Examiner Name Wai Sing Louie

Attorney Docket Number AMAT/6303.02/CPICOPPER/PJS

Sheet 1

of

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Submission Date

August 31, 2004

**U.S. PATENT DOCUMENTS**

Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
	A1	US-6686271 B2	02/03/2004	Raaijmakers, et al.	
	A2	US-6660660 B2	12/09/2003	Haukka, et al.	
	A3	US-6632279 B1	10/14/2003	Ritala, et al.	
	A4	US-6630201 B2	10/07/2003	Chiang, et al.	
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Group Art Unit	2814
Examiner Name	Wai Sing Louie
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	A55	US-20040018304 A1	01/29/2004	Chung, et al.	
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Application Number

09/963,373

Filing Date

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First Named Inventor

Chung, et al.

Group Art Unit

2814

Examiner Name

Wai Sing Louie

Attorney Docket Number

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1 P **SUPPLEMENTAL INFORMATION  
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	A83	US-20030134508 A1	07/17/2003	Raaijmakers, et al.	
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Examiner Name	Wai Sing Louie
Attorney Docket Number	AMAT/6303.02/CPICOPPER/PJS
Submission Date	August 31, 2004

**U.S. PATENT DOCUMENTS**

Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
	A139	US-20020106846 A1	08/08/2002	Seutter, et al.	
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Substitute for form 1449A/PTO

Application Number

09/963,373

Filing Date

September 26, 2001

First Named Inventor

Chung, et al.

Group Art Unit

2814

Examiner Name

Wai Sing Louie

Attorney Docket Number

AMAT/6303.02/CPICOPPER/PJS

**SUPPLEMENTAL INFORMATION  
DISCLOSURE STATEMENT BY  
APPLICANT**

(use as many sheets as necessary)

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of

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Submission Date

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Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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	A167	US-20010028924 A1	10/11/2001	Sherman	
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	B1	EP 1,142,894 A2	10/10/2001	Morman, et al.		
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**SUPPLEMENTAL INFORMATION  
DISCLOSURE STATEMENT BY  
APPLICANT**

(Use as many sheets as necessary)

Sherman

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of

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Application Number	09/963,373
Filing Date	September 26, 2001
First Named Inventor	Chung, et al.
Group Art Unit	2814
Examiner Name	Wai Sing Louie
Attorney Docket Number	AMAT/6303.02/CPICOPPER/PJS
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	B16	WO 02/45871 A1	06/13/2002	Chiang, et al.		
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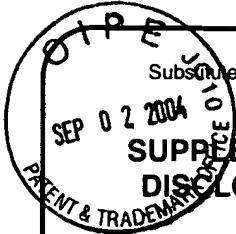
**NON PATENT LITERATURE DOCUMENTS**

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	C2	Chang-Wook, et al. "Growth and Characterization of Aluminum Oxide (Al <sub>2</sub> O <sub>3</sub> ) Thin Films by Plasma-Assisted Atomic Layer Controlled Deposition," J. Korean Inst. Met. Mater., Vol. 38, No. 10, Oct. 2000 pp.1395-1399	
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 <p>Substitute for form 1449A/PTO <b>SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)</p>		Application Number	09/963,373		
		Filing Date	September 26, 2001		
		First Named Inventor	Chung, et al.		
		Group Art Unit	2814		
		Examiner Name	Wai Sing Louie		
		Attorney Docket Number	AMAT/6303.02/CPICOPPER/PJS		
Sheet	9	of	9	Submission Date	August 31, 2004

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	C16	Paranjpe, et al. "Atomic Layer Deposition of AlO <sub>3</sub> for Thin Film Head Gap Applications," J. Elec. Soc., Vol. 148, No. 9 Sept., 2001 pp. G465-471	
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